NOV 0 3 2006 BY THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Confirmation No. 1632

Norio KIMURA et al.

Attorney Docket No. 2001-0660A

Serial No. 09/864,208

Group Art Unit 1763

Filed May 25, 2001

Examiner Jeffrie R. Lund

SUBSTRATE POLISHING APPARATUS AND

Mail Stop: AF

SUBSTRATE POLISHING METHOD

PETITION FOR THIRD MONTH'S EXTENSION OF TIME

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

THE COMMISSIONER IS AUTHORIZED TO CHARGE ANY DEFICIENCY IN THE FEES FOR THIS PAPER TO DEPOSIT ACCOUNT NO. 23-0975

Sir:

Petition hereby is made for a three month extension of time to respond to the communication of May 3, 2006.

The fee of \$570.00 is

- (X) submitted herewith.
- to be charged to Deposit Account No. 23-0975. A duplicate copy of this Petition is enclosed.
- () Small entity status of this application is established by a Small Entity Status Assertion which
 - () is enclosed.
 - () has been previously submitted.

Respectfully submitted,

Norio KIMURA et al.

Nils E. Pedersen

Registration No.33,145

Attorney for Applicants

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